

Resource Summary Report

Generated by RRID on Aug 5, 2026

Oxford: Ionfab 300 IBD Plasma Technology

RRID:SCR_020362

Type: Tool

Proper Citation

Oxford: Ionfab 300 IBD Plasma Technology (RRID:SCR_020362)

Resource Information

URL: <https://plasma.oxinst.com/products/ald/flexal#product-information-tabs>

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Description: Ion beam deposition products produce deposited films with high quality, dense and smooth surfaces. Ion beam technology provides approach to etch and deposition by offering single tool and maximising system utilisation, which includes open load, single substrate load lock, and cassette to cassette.

Resource Type: instrument resource

Keywords: Oxford, Plasma Technology, Instrument, Resource equipment, Equipment, USEDit,

Availability: Commercially available

Resource Name: Oxford: Ionfab 300 IBD Plasma Technology

Resource ID: SCR_020362

Alternate IDs: Model_Number_Ionfab_300_IBD

Record Creation Time: 20220129T080349+0000

Record Last Update: 20260801T190645+0000

Ratings and Alerts

No rating or validation information has been found for Oxford: Ionfab 300 IBD Plasma Technology.

No alerts have been found for Oxford: Ionfab 300 IBD Plasma Technology.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.